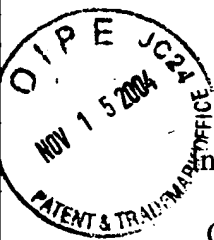


**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**



In re Application of:

Christine Hau-Riege, et al.

:

Group Art Unit: 2823

Application No.: 10/697,214

:

Examiner: William M. Brewster

Filed: October 29, 2003

:

Title: SEMICONDUCTOR COMPONENT AND METHOD FOR PRECLUDING STRESS-INDUCED VOID FORMATION IN THE SEMICONDUCTOR COMPONENT

Mail Stop Amendment  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

**RESPONSE TO RESTRICTION REQUIREMENT TRANSMITTAL**

1. Transmitted herewith is a Response to Restriction Requirement for this application.

2. Applicant believes there are no additional fees required for these filings. The Commissioner is hereby authorized to charge any deficiency to Deposit Account No. 50-2173. A duplicate copy of this Transmittal Letter is enclosed.

Respectfully submitted,

Dated: 10 November 2004

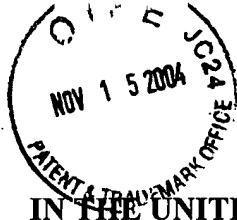
*Rennie William Dover*  
Rennie William Dover, Reg. No. 36,503  
THE CAVANAGH LAW FIRM  
1850 N. Central Avenue, Ste. 2400  
Phoenix, Arizona 85004  
Telephone: (602) 322-4000

CERTIFICATE OF MAILING UNDER 37 C.F.R. § 1.8

I hereby certify that this document (and any as referred to as being attached or enclosed) is being deposited with sufficient postage as first class mail with the United States Postal Service on November 10, 2004 and addressed to Mail Stop Amendment, Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450.

I hereby declare that all statements made herein of my own knowledge are true and that all statements made on information and belief are believed to be true; and further that these statements were made with the knowledge that willful false statements and the like so made are punishable by fine or imprisonment, or both, under Section 1001 of Title 18 of the United States Code, and that such willful false statements may jeopardize the validity of the application or any patent issued thereon.

*Allen T. [Signature]*



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**RESPONSE TO RESTRICTION REQUIREMENT**

Mail Stop Amendment  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

In response to the Office action mailed October 28, 2004, please amend the application as follows: